

Datasheet: 739174-W19

Macroporous silicon membrane

Etching

Type:	lift-off membrane
Size:	6 inch
Pitch:	1.5 μm trigonal
Thickness:	68 μm membrane thickness
Shape:	straight
Diameter:	1 μm

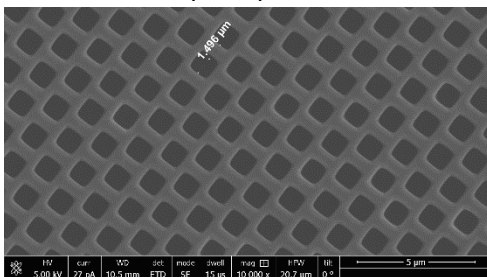
Postprocessing

- Membrane lift-off
- Laserdicing 10.0 mm x 10.0 mm

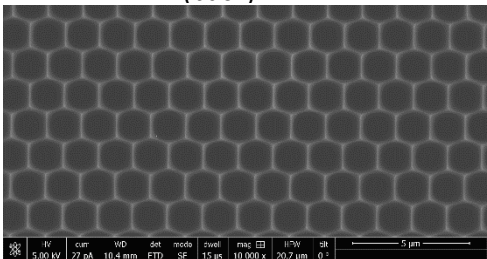
Measurements (SEM)

Top view

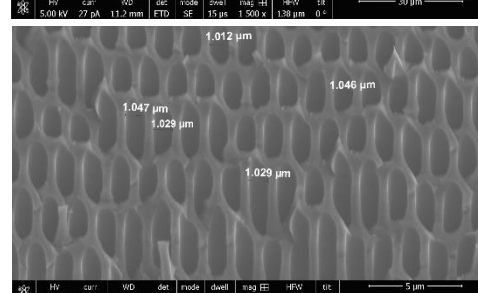
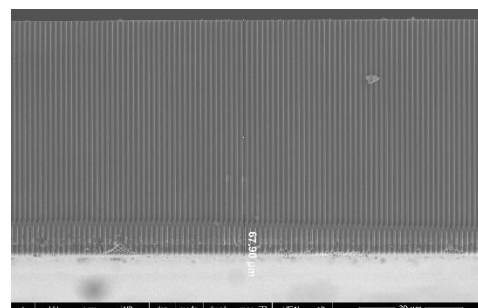
(front)



(back)



Side view



Remarks

- Lifted backsides are sensitive to mechanical handling. Abrasion of silicon nanotips is visible as brown “scratches” on the surface but have minor effect on the underlying pores. We suggest using vacuum tweezers on the front side. Depending on the thickness, flat tips with small diameters are preferred instead of suction cup tips to minimize mechanical stress.
- Please be aware: Membranes <50 μm thickness may flip due to electrostatic forces while opening or closing transport boxes!

08/02/2018 M.Christl

(If not specified separately standard tolerances of $\pm 10\%$ will apply)